## QED <br> Technologies



## Outline

## QED

\& Overview of Magnetorheological Finishing (MRF) * MRF Applications

* Jet Finishing
\& Subaperture Stitching Interferometer (SSI)
* SSI Applications
* Conclusions


## Magnetorheological Finishing (MRF) 〇ED <br> Technologies




## Q22-Y Raster MRF System

Qvarious applications for non-round optics are enabled by rastering (e.g. cylinders, prisms, free forms...)
W. The Q22-Y has all of the capabilities of the Q22X plus the ability to polish:


## MRF - Breakthrough Technology

## The MRF polishing tool:

- never dulls or changes
- is interferometrically characterized
- is easily adjusted
- conforms to part shape - works on complex shapes (flat, sphere, asphere, cylinder...)
- has high removal rates
- Has a removal based on shear stress so applies very low normal load on abrasive, improving surface integrity
- Is very deterministic, leading to high convergence rate
- These attributes lead to a production oriented, deterministic, computer controlled polishing and figuring technique.
- Production proven: more than 100 machines worldwide


## MRF Process Flow Diagram

$\operatorname{removal}(x, y)=d w e l l(x, y) \otimes \operatorname{spot}(x, y)$
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Removal Function


QED Software


MRF Machine Instructions


Surface after MRF
Suction
Predicted Surface


Pump


Electromagnet

MR fluid conditioner

## QED MRF Product Line

 100+ machines in use, many flavors...

- Q22-XE-Up to 80 mm in diameter
- Q222X - Up to 200 mm in diameter
- Q22Y - Q 22 X + Raster tool path
- Q22 400 X - Up to 400 mm in diameter
- Q22750P2 - Plano optics up to 750 mm $\times 1000 \mathrm{~mm}$ in size
- Q22:950F-Free-form optics up to $\sim 950 \mathrm{X}$ 1.250 mm
- The next-generation, meter-class machine is being built to finish free form optics
- Q22-xx*x:-Multi-meters freeform
- SSI-Sub-aperture Stitching Interferometer (SSI) for high precision metrology


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## High Precision

CaF2 Lenses for 157nm Lithography

<111> Element
Surface figure: 0.57 nm rms

<100> Element
Surface figure: 0.63 nm rms


I-19489.ILL

$\longrightarrow$


Jan Mulkens (ASML), et al., "Optical lithography solutions for sub-65 nm semiconductor devices", Proc. of SPIE, 5040; pp: 753-762, 2003.

## Transmitted Wavefront Correction

 Fused Silica Right angle prism

$p-v: 0.024 \lambda$

## Transmitted Wavefront



## Improve SPDT surfaces

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## Roughness

## Cerium oxide or diamond based fluids



High Pass Filter (FTT Fixed - 12.5 1/mm)

| Rmax | 44.692 | $\AA$ |
| :--- | :--- | :--- |
| $\operatorname{Ra}$ | 2.829 | $\AA$ |
| Rq | 3.575 | $\AA$ |

Inse Rus (Rq) 0.176 nm Ing. Ra 0.136 nm Ing, Rmax 1.884 nM

Fused silica - round flat, 0.5 mm DC-run polishing

## Improvements in Surface Integrity

Residual stress removal

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From: "Magnetorheological Finishing (MRF) to Relieve Residual StressandSubsurface Damage on Silicon Wafers", by StevenR: Arrasmith, Stephen D.Jacobs, Johm C. Lambropoulos, Alexander Maltsev, Donald Golini and William I. Kordonski:

## MIT Lincoln Lab

157 nm Laser Damage Study on CaF2






Improvements in Surface Integrity National Ignition Facility (NIF) at LLNL
$\square$


## MRF polished and etched parts

Highest quality conventional polish


MRE polished part


Dark-field microscopy of etched MRF surfaces shows a near-absence of the sub-surface damage normally associated with conventional finishing

## Aspheres

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## Spherical vs. Aspheric Optics



Aspheric optics provide performance advantages.


Aspheric Correction


Pictures from the Hubble Space Telescope

## MRF's Unique Attributes

## MRF's unique attributes...

MR Fluid properties are Precisely Controlled.
MRF tool is Subaperture.
therefore
MRF is Deterministic.

## Lead to a unique asphere manufacturing capability

## MRF Asphere Manufacturing:

1. "Mild" aspheres - Aspherize from a best fit sphere and figure correct
2. "Wild" aspheres - MRF figure correction following:

- Diamond turning to aspheric
- Ground aspheric shape
- Intermediate pre-polish step
- Direct from grind (in some cases)


## Aspherizing from Best Fit Sphere

 Asphere polishing with MRF- Spot shape = F (local curvature)
- Impossible for conventional pads
- Algorithms to "morph" spot



## MRF Aspherizing - "mild" aspheres

 Complete Asphere Manufacturing- MRF "aspherizes" or polishes in the aspheric shape from a best fit sphere
- MRF then figure corrects the optic


## Before

\&Hyperbola (conic constant $=-1.355$ )
KOD 70 mm , CA 64 mm
-Convex base radius, $R=272.539 \mathrm{~mm}$
-Best fit radius $=274.059 \mathrm{~mm}$ (at an aperture of 70 mm)
*Aspheric departure $=3.1 \mathrm{\mu m}$ (from best fit sphere)
Deviation from asphere


P-V N10, rms N 160
(over the 64 mm CA in reflection)

## MRF Aspherizing - "mild" aspheres

 BK7 Aspheres produced with MRF

- Aspheres are 110 mm diameter with 11 microns of departure.
- Total run time was -5 hours per lens.


## Large Optics

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- Optics getting larger and larger
- Size and/or number of segments increasing
\&Manufacturing time decreasing
- From month(s) $/ m^{2}$ to day(s) $/ m^{2}$

Ancreasing light-weighted structures

- From 100's $\mathrm{kg} / \mathrm{m}^{2}$ to $<10 \mathrm{~kg} / \mathrm{m}^{2}$
- Decreasing face-sheet thickness
- New materials (e.g. SiC, Be, porous Si etc.)


## -Specifications tightening

- Figure, mid-spatial frequency and roughness
- Edge exclusion going to zero (for segment design)

- More challenging shapes: aspheres, offraxis etc.


## Wosts decreasing

## Q22-750P2 Polishing

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## Light-weighted optics

MRF Fixing quilting errors


## Light-weighted optics

## MRF Fixing quilting errors - Add'l examples



Hextek Gas FusionTM Borosilicate $15 \mathrm{~kg} / \mathrm{m}^{2}$ mirror blank
Correct cryo-quilting


Coors I ek lightweight SiC mirror $20 \mathrm{~kg} / \mathrm{m}^{2}$

## Q22-950F Large Asphere Polishing

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- Asphere ~ 1,300 um $(1.3 \mathrm{~mm})$ ) of departure from BFS
- Fused Silica
884.0 mm in diameter



## Asphere Polishing Video

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## SOI Wafer

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## Thick film 150 mm SOI wafer

Initial Condition


Thickness: $5.36 \mu \mathrm{~m}$ with TTV of $1.131 \mu \mathrm{~m}$


Thickness: $3.07 \mu \mathrm{~m}$ with TTV of $0.144 \mu \mathrm{~m}$

## Thin film 200 mm SOI Wafer

## Thickness variation



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## MR Jet Polishing

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- For special geometries
* Jet of MR fluid
\&. Polish steep/decp concave surfaces
-. Polish magnetic materials
* Stable spot over large range of standoff distances
- Same shear-based removal process


## MR Jet ${ }^{\text {TM }}$ Prototype



MR Fluid. Magnet


MR Fluide
Magnet on

-A fluid jet can be stabilized by using a magnetorheological fluid and a magnetic field

Whis stabilized jet gives significant advantages in finishing complex shapes
$\mathcal{C}$ Contained in the CNC machine with stable delvery system, MR Jet is used for polishing challenging shapes to high precision

## MR Jet Removal Function Stability



- Stability provided by MR Jet enables deterministic finishing at large stand-off distances


## Polishing Inside an Ogive Dome



## Dome Polish - MR Jet



## FS Dome Polish - MR Jet Results



97 mm OD, 2.5 mm thick fused silica dome in MR Jet Machine-

tritial
$408 \mathrm{~mm} \mathrm{P-V}$
50.3 mm RMS


Final
42.5 mm P-V
6.1 mm RMS

- Improved figure error from 408 nm PVV ( 50.2 nm RMS) to 42.5 nm P.V ( 6.1 nm RMS)
- MR Jet was able to polish this high aspect ratio dome to high precision
- This technique provides an opportunity to correct the concave surface of a dome, and other challenging shapes, to high precision
- Future applications will include more aerodynamic conformal shapes


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## Innovative Metrology: SSI

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## - Full aperture measurement of large NA \& CA parts

Completely Automatic

- Auto-Positioning, nulling, \& radius testing

Q Intuitive \& Easy to Operate
*- Reference wave, distortion, pixel scale

## Reference



## Large Aperture Metrology

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Large aperture lens mounted in QED's SSI.


Schematic representations of a six-axis platform for performing stitching interferometry on large aperture convex and concave parts.

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## Stitching a Large AION Dome

 Lattice \& Motions```
Aperture - 148.34 mm (5.84")
Radius - 82.55 mm (3.25")
    CT - 3.04 mm (0.12")
Sag - 50.39 mm (1.984")
```

Fl0. 55


Objective - Zygo - 4 ${ }^{1 / 111.5}$
Subaperture $=55.1 \mathrm{~mm}$
Required 25 subapertures -


Determine Optical Testability

$$
\text { (4 center, } 9 \text { inner, } 12 \text { outer) }
$$



Design Measurement

## Stitching a Large AION Dome Results



Radius: 82.6 mm
Surface:
PV - $1.649 \lambda$ (@ 68Bnm $)$
Runs - 0.187 $\lambda$ (@ 6B8nns)
Total measurement time:
12 minutes!!

## Full Aperture Stitched Result

Reference Wave Error


## MRF/SSI Hemisphere Demonstration

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## SSI measurement process

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Measure


Full-aperture map

## Measuring High Precision Spheres




Aperture: $200 \mathrm{~mm}\left(8.0^{\prime \prime}\right)$
Radius: 500 mm (19.7")
CT: 34 mm (1.3 ${ }^{\mathrm{HI}}$ )

Subaperture: 69.4 mm
Extension Factor: 2,95
Required subapertures: 30
(4 center, 11 inner, 15 outer)

## The Stitched Result

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| (1) zyso | Surface/Wavefront Kap | 4 |
| :---: | :---: | :---: |
| 1.2 2ygo | Billed Plot | 4 |



Radius: 499.9765 mm
Surface: $P V=0.060 \lambda$ (@ 633nm) RMS = $0.004 \lambda$ (@ 633nm)
Total measurement time: 25 minutes!!

## Summary

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- Boosted testable aperture sizes (i.e. costeffective reference optics)
- Boosted testable aspheric departure (can obviate need for nulls)

8. Boosted accuracy (from thorough, automated calibration of reference wave, distortion, retrace, etc.)

- Boosted resolution

Q- Reduced non-common air path for long-radius concaves


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## Conclusions

- MRE:
- Shaping - high precision figure correction
- From real small to real large optics
- Improve surface integrity
- Thickness control - substrates, or thin/thick films
- Jet Finishing:
- For difificult geometries
- Or new materials
- SSI:
- Metrology solution for small to large optics
- Including hemispheres and other high NA parts


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